

Electronic Patent Application Fee Transmittal

Application Number:	10585229			
Filing Date:				
Title of Invention:	System and method for selective etching of silicon nitride during substrate processing			
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Filer:	Brian L. Belles/Kathleen Fletcher			
Attorney Docket Number:	ARK002-108430.040-US			
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Miscellaneous-Filing:				
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Petition:				
Patent-Appeals-and-Interference:				
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Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Total in USD (\$)				65